

High yield hydrogen production enabled by macroporous silicon monoliths

Vega D.^a, Divins N.^b, Trifonov T.^a, Rodriguez A.^a, Llorca J.^b

a Department of Electronic Engineering, Universitat Politècnica de Catalunya, Campus Nord b Department of Chemical Engineering , Universitat Politècnica de Catalunya, Campus EEBE Contact@E-mail: angel.rodriguez@upc.edu

Abstract

A macroporous silicon (MPS) membrane of 210 μ m thickness was functionalized and evaluated for hydrogen production by steam reforming of various fuels. Performance is comparable to conventional reactors, but in a much compact device thanks to process intensification [1]. No blockage or damage was observed after extensive testing. MPS technology [2] is well suited for applications as demonstrated in [3], as it allows the fabrication of large arrays of regular pores in a silicon substrate. The fabricated samples consist of an array of ordered pores of 3.3 μ m in diameter and 210 μ m length, with a straight profile; the array periodicity is 4 μ m. The as-etched sample was post-processed to create an open membrane, and later, it was conformally covered with a CeO₂ film, which was then coated with a layer of RhPd nanoparticles. Different fuels were studied for hydrogen generation at high temperatures (up to 1023 K): ethanol, propanol, acetone, acetic acid, 2-methoxythanol, and a diesel surrogate [4]. Total tests duration was 80 h. The results show that no structural damage nor channel blockage is present. Results of H₂ production are shown in **Fig. 1**. The reaction hydrogen yield and selectivity show the best results for 2-methoxyethanol at 923 K, with 53% selectivity, $\theta_{H_2} = 0.4$ yield, and a H₂ production density of 110 L_N H₂/mL_{fuellin}. cm³_{act}.

Comparable results in hydrogen production with respect to conventional ceramic honeycombs have been obtained, but in a much smaller volume. Good performance was obtained and no damage or blockage was observed after extended testing, making this technology an outstanding candidate for energy production in embedded applications.

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References

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